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INFORMATION DISCLOSURE STATEMENT BY APPLICANT

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Sheet 1 of 4 sheets

Complete if Known

Application Number	10/029,373
Filing Date	12/20/2001
First Named Inventor	Chung J. Lee
Group Art Unit	
Examiner Name	
Attorney Docket Number	108324.00007 DIEL-0006

U.S. PATENT DOCUMENTS

Examiner Initials *	Cite No. ¹	Document Number	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number - Kind Code ² (if known)			
<i>M-P</i>	1	SN 09/925,712	08/09/2001	Lee	Entire Content
<i>gm-P</i>	2	US 3,268,599	08/23/1966	Chow	Entire Content
<i>gm-P</i>	3	US 3,274,267	09/20/1966	Chow	Entire Content
<i>gm-P</i>	4	US 3,280,202	10/18/1966	Gilch	Entire Content
<i>gm-P</i>	5	US 3,288,728	11/29/1966	Gorham	Entire Content
<i>gm-P</i>	6	US 3,332,891	07/25/1967	Chow et al.	Entire Content
<i>gm-P</i>	7	US 3,342,754	09/19/1997	Gorham, et al.	Entire Content
<i>gm-P</i>	8	US 3,349,045	10/24/1967	Gilch	Entire Content
<i>gm-P</i>	9	US 3,379,803	04/23/1968	Tittmann, et al.	Entire Content
<i>gm-P</i>	10	US 3,503,903	03/31/1970	Shaw, et al.	Entire Content
<i>gm-P</i>	11	US 3,509,075	04/28/1970	Niegish et al.	Entire Content
<i>gm-P</i>	12	US 3,626,032	12/07/1971	Norris	Entire Content
<i>gm-P</i>	13	US 3,694,495	09/26/1972	Norris	Entire Content
<i>gm-P</i>	14	US 3,940,530	02/24/1976	Loeb et al.	Entire Content
<i>gm-P</i>	15	US 5,268,202	12/07/1993	You, et al.	Entire Content
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<i>gm-P</i>	17	US 5,879,808	03/09/1999	Wary, et al.	Entire Content
<i>gm-P</i>	18	US 5,958,510	09/28/1999	Sivaramakrishnam,	Entire Content
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<i>gm-P</i>	20	US 6,140,456	10/31/2000	Foggiator	Entire Content
<i>gm-P</i>	21	US 6,265,320	07/24/2001	Shi, et al.	Entire Content

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Examiner Initials*	Cite No. ¹	Foreign Patent Document	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	T ⁶
		Country Code ³ - Number ⁴ - Kind Code ⁵ (if known)				
gm-p	22	EP 0 349 032 A2	01/03/1990	Van der Werff,	/	
gm-p	23	EP 0 523 479 A2	01/20/1993	Lawrence, et al.		
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gm-p	25	GB 650 947	03/07/1951	Szwarc		

Examiner
Signature

Mark Patton

Date
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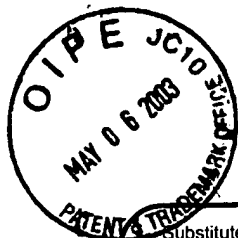
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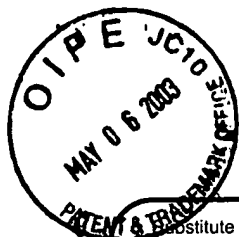
Examiner Initials *	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
<i>h.p.</i>	34	BRUN A.E. 100NM: THE UNDISCOVERED COUNTRY, SEMICONDUCTOR INTERNATIONAL, P79, FEB. 2000	
<i>h.p.</i>	35	CHOW, S. W., et al., "The synthesis of 1,1,2,2,9,9,10,10-octafluorou2, 2Paracyclophane" Journal of Organic Chemistry, American Chemical Society. Easton, US Vol 35(1), 1970 pages 20-22.	
<i>h.p.</i>	36	CHOW, S. W., et al., "Poly (a,a,a',a'-tetrafluoro-p-xylylene)," Journal of Applied Polymer Science, New York, NY< US, Vol. 13, No. 9, 1969, pgs. 2325-2332.	
<i>h.p.</i>	37	YANG, G.-R. et al., "High Deposition Rate Parylene Films," Journal of Crystal Growth, North-Holland Publishing Co., Amsterdam, NL, Vol. 183, No. 3, 1998, pgs. 385-390	
<i>h.p.</i>	38	GREINER, A, "Poly(1,4-xylylene)s: Polymer Films by Chemical Vapour Deposition," Trends in Polymer Science, Elsevier Science Publishers B. V. Amsterdam, NL, Vol. 5, No. 1, 1997, pgs. 12-16	
<i>h.p.</i>	39	HARRUS, A. S., et al., "Parylene Af-4: A Low ϵ_r Material Candidate for ULSI Multilevel Interconnect Applications," Material Research Society Symposium Proceedings, Vol. 443, 1997	
<i>h.p.</i>	40	IWAMOTO, R., et al., "Crystal Structure of Poly-p-xylylene. I. The a Form," Jour. Polymer. Sci. Polymer. Phys. Ed., Vol. 11, (1973), pgs. 2403-2411.	
<i>h.p.</i>	41	IWAMOTO, R., et al., "Crystallization During Polymerization of Poly-p-xylylene. III. Crystal Structure and Molecular Orientation as a Function of Temperature," Jour. Polymer. Sci. Polymer. Phys. Ed., Vol. 13, (1975), pgs. 1925-1938.	
<i>h.p.</i>	42	LANG, C.-I, "Vapor Deposition of Very low k Polymer Films, Poly (Naphthalene), Poly (Fluorinated Naphthalene)" Materials Research Society Symposium Proceedings, Materials Research Society, Pittsburgh, PA US, Vol. 381, 17 April 1995 (1995-04-17), pgs. 45-50	
<i>h.p.</i>	43	LEE C. J. "Polyimides, polyquinolines and polyquinoxalines: Tg-Structure Relationships" Macromol. Chem. Phys. C29(4) 431-560 (1989)	
<i>h.p.</i>	44	LEE, C, "TRANSPORT POLYMERIZATION OF GASEOUS INTERMEDIATES AND POLYMER CRYSTALS GROWTH", J. MACROMOL. SCI-REV. MACROMOL. CHEM., C16 (1), 79-127 (1977-78), PP79-127)	
<i>h.p.</i>	45	MATHUR, D., et al., "Vapor Deposition of Parylene-F Using Hydrogen as Carrier Gas," Journal of Materials Research, Vol. 14, No. 1, 1999, pgs. 246-250	

Examiner Signature	<i>Marc Patterson</i>	Date Considered	<i>1/6/02</i>
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PTO/SB/08B(10-01)
Approved for use through 10/31/2002. OMB 0651-0031
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Sheet	4	of	4 sheets	Attorney Docket Number	108324.00007 DIEL-0006

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Examiner Initials *	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
M.P.	46	MORGEN, M., et al., "Morphological Transitions in Fluorinated and Non-Fluorinated Parylenes," Material Research Society Symposium Proceedings, Vol. 565, 1999, pgs. 297-302	
M.P.	47	PENG Z., AND MCGIVERN, SEAN., "QUANTUM YIELDS AND ENERGY PARTITIONING IN THE UV PHOTODISSOCIATION OF HALON 2402", JOUR. OF CHEM. PHYS. VOL 113, NO.17, P7149-7157 (2000).	
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M.P.	50	RIEDEL, W., "ELECTRO-LESS NICKEL PLATING 2 ND EDITION", ASM INTERNATIONAL, FINISHING PUBLICATION LTD. 1998	
M.P.	51	RYAN, E. T., et al., "Effect of Deposition and Annealing on the Thermomechanical Properties of Parylene Films," Material Research Society Symposium Proceedings, Vol. 476, 1997, pgs. 225-230	
M.P.	52	SHARMA, A. K., et al., "Optimizing Poly(chloro-p-Xylylene) or Parylene C Synthesis," Journal of Applied Science, John Wiley and Sons, Inc., New York, US, Vol. 36, No. 7, Sept. 20, 1988, pgs. 1555-1565	
M.P.	53	WARY J, ET AL., POLYMER DEVELOPED TO BE INTERLAYER DIELECTRIC, SEMI-CONDUCTOR INTERNATIONAL, 211-216, JUN. 1996.	

Examiner Signature	<i>Marc Petter</i>	Date Considered	1/6/04
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